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(54) **SCATTERING-ASSISTED SUPER-LOCALIZATION MICROSCOPY METHOD AND RESPECTIVE APPARATUS**

VERFFAHREN UND VORRICHTUNG FÜR DIE STREULICHTUNTERSTÜTZTE
SUPERLOKALISIERUNGSMIKROSKOPIE

PROCÉDÉ ET DISPOSITIF POUR LA MICROSCOPIE À SUPERLOCALISATION SUPPORTÉE PAR
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• **JI N ET AL: "Adaptive optics via pupil segmentation for high-resolution imaging in biological tissues", NATURE METHODS, vol. 7, no. 2, 27 December 2009 (2009-12-27), pages 141-147, XP055138052, ISSN: 1548-7091, DOI: 10.1038/nmeth.1411 cited in the application**

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Description

[0001] The present invention relates to a method for increasing the optical resolution of a fluorescence microscopy apparatus, on opaque or scattering sample, without increasing the apparatus complexity, in a simply, reliable, adaptable, and economical way.

[0002] Such a method exploits the light scattered by the sample itself to increase the effective numerical aperture of the microscopy apparatus overcoming the resolution of the used light collection optical system, i.e. the objective. Such a method is based on the wavefront phase and/or amplitude modulation of an exciting coherent light beam on a scattering sample for building constructive interference out of light beams scattered by the sample, causing a tight focus, and on the control of the light scattered by the sample. In particular, the method according to this invention maximizes the intensity of a fluorescent signal emitted by fluorescent proteins of a biological tissue and assembles information obtained from the fluorescence generated by multiple foci generated in different position across the sample after repeated optimizations into an image whose resolution is not limited by the illumination and collection optics.

[0003] Further, this invention relates to a fluorescence microscopy apparatus with increased optical resolution.

[0004] Although the presented invention is mainly oriented towards the investigation of biological samples where the experimental conditions require the fluorescence signal collection optics to be positioned distant from samples, it must be borne in mind it may be applied to fluorescence signal generated by other scattering samples, in other fields such as for instance astronomic and atmospheric, or survey at distance for security or civil application, still remaining within the scope of protection as defined by the annexed claims.

[0005] The diffraction limit, as formulated by Abbe and Rayleigh, states that the maximum resolution achievable by a lens is defined by the numerical aperture, NA . The larger the solid angles of the illumination and collection optics, the higher the spatial resolution achievable by an imaging system. Papers of Tang et al. "Superpenetration optical microscopy by iterative multiphoton adaptive compensation technique", Proceedings of the National Academy of Sciences 109, 8434-8439 (2012) and of Ji N. et al "Adaptive optics via pupil segmentation for high-resolution imaging in biological tissues", Nature methods 7, 141-147 (2010) disclose how to correct optical aberrations with adaptive optics for obtaining the theoretical resolution of a real lens. Such as theoretical resolution may be bypassed by super resolution techniques, as disclosed by papers of Betzig, E. et al. "Imaging intracellular fluorescent proteins at nanometer resolution." Science 313, 1642-1645 (2006), of Hell, S. W. & Wichmann, N. "Breaking the diffraction resolution limit by stimulated emission: stimulated-emission-depletion fluorescence microscopy." Optics letters 19, 780-782 (1994), of Schermelleh, L. et al "A guide to super-resolution fluores-

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[0006] Another example of fluorescence microscopy method and a relative apparatus of the prior art is described in the paper of Izeddin, I. et al. "PSF shaping using adaptive optics for three-dimensional single-molecule super-resolution imaging and tracking." Optics Express Vol. 20, Issue 5, pp. 4957-4967 (2012).

[0007] The suggested solutions suffer from several drawbacks. First, the maximum resolution, which may be achieved through conventional optical microscopy apparatus, requires a lens positioned close to the sample, which may be a severe limitation in non-invasive and in-vivo measurements. Moreover, a high numerical aperture NA is an essential ingredient in most present microscopies yet aiming to bypass the diffraction limit, such as confocal, near field, structured illumination, stimulation emission depletion, or photo-activated localization microscopy. Finally, the scattering, for example from opaque tissue, is usually seen as an obstacle for these microscopies perfect focusing, degrading the wavefront shape by optical aberrations and limiting the achievable resolution. For example, the most vertebrate tissues (including humans) appear optically opaque so that a coherent light beam entering a portion of skin is diffused into many uncorrelated optical paths and after a certain distance (the transport mean free path, ℓ) their travel direction is completely randomized.

[0008] It is an object of this invention to overcome the described drawbacks, allowing in a reliable, simple and economical way to increase the optical resolution of a fluorescence microscopy apparatus, independently of the numerical aperture NA of the microscope optics and in a non-invasive way.

[0009] It is specific subject matter of the present invention a fluorescence microscopy method comprises the following steps:

- A. illuminating a scattering sample including one or more fluorescent emitters with a coherent excitation light beam having a wavefront with a first initial configuration C^1 for exciting said one or more fluorescent emitters comprised in the scattering sample;
- B. acquiring a first initial image F^1 corresponding to a background image $F^1 = F_B$ of the scattering sample, through a pixel imaging unit, obtaining a speckle

grain image;

C. selecting M target pixels P_N , with $N = 1, \dots, M$, of coordinates $[X_N, Y_N]$ belonging to an area of the first initial image F^1 having fluorescence signals of at least one fluorescent emitters, each one of the M target pixels P_N having a first initial intensity I_{PN}^1 ;

D. optimising the first initial configuration of the wavefront for each one of the M target pixels P_N , for decreasing the speckle grain size of the first initial image F^1 and obtaining a final image $F^{fin}(I_{PN}^{max})$ of the scattering sample with a local maximum I_{PN}^{max} of the fluorescence signal corresponding to a maximum intensity of the target pixels P_N ;

E. subtracting the first initial image F_B of background, obtained at step B, from the final image $F^{fin}(I_{PN}^{max})$, obtained at step D, for each one of the M target pixels P_N , obtaining an image $F_{speckle(PN)}$ having only fluorescent signals coming from a speckle grain located at pixel $[X_N, Y_N]$ with intensity $I_{PN}^{speckle}$, for each one of the M target pixels P_N ;

F. fitting the image $F_{speckle(PN)}$, obtained at step E, with a Gaussian function with free center coordinates, for each one of the M target pixels P_N , thereby obtaining coordinates (X_N, Y_N) and intensity I_N in a xy plane;

G. generating an image F_N containing a Gaussian distribution centered at coordinates (X_N, Y_N) and with intensity I_N , obtained at step F, and with a waist equal to an average size S of speckle grain of the scattering sample, for each one of the M target pixels P_N ;

H. generating a final image of the sample by summing the M images F_N obtained at step G, for each one of the M target pixels P_N .

[0010] According to another aspect of the invention, step D may comprise, for each one of the M target pixels P_N , the following sub-steps:

D.1 - set the first initial configuration C^1 of the wavefront as a reference configuration $C^1 = C^{ref}$ of the wavefront, the first initial image F^1 as a reference image $F^1 = F^{ref}$, and a first intensity I_{PN}^1 at the target pixel P_N of the first initial image F^1 as a reference intensity $I_{PN}^1 = I_{PN}^{ref}$ at the target pixel P_N ;

D.2 - repeating T times, with $T > 1$, the following cycle of substeps:

D.2.1 - varying the reference configuration C^{ref} of the wavefront through an amplitude and/or phase modulation unit (10) so as to obtain an i-th configuration C^i of the wavefront;

D.2.2 - acquiring an i-th image F^i with an i-th intensity I_{PN}^i at the target pixel P_N ;

D.2.3 - checking whether the i-th intensity I_{PN}^i value at the target pixel P_N is greater than the reference intensity I_{PN}^{ref} thereby:

if $I_{PN}^i > I_{PN}^{ref}$, then the i-th configuration C^i of

the wavefront obtained at step D.2.1 is accepted as the reference configuration C^{ref} of the wavefront, i.e. $C^{ref} = C^i$, and $F^{ref} = F^i$ and $I_{PN}^{ref} = I_{PN}^i$ are set, else

if $I_{PN}^i < I_{PN}^{ref}$, then the i-th configuration C^i of the wavefront obtained at step D.2.1 is not accepted, and the reference configuration C^{ref} of the wavefront before the variation performed at step D.2.1 is restored;

D.3 - setting the reference image F^{ref} as the final image $F^{ref} = F^{fin}(I_{PN}^{max})$ and the reference intensity I_{PN}^{ref} as a local maximum I_{PN}^{max} of fluorescence signal at the target pixel P_N .

[0011] According to a further aspect of the invention, said amplitude and/or phase modulation unit may be a digital micromirror device comprising a $p \times q$ matrix of micromirrors and the step D.2.1 is implemented by varying the orientation of $Q \geq 1$ micromirrors of the digital micromirror device, thereby $Q \leq p \times q$, wherein each micromirror can take on $V > 2$ orientations, so that $T = V \times Q$.

[0012] According to an additional aspect of the invention, said average size S of the speckle grain of the scattering sample may be set equal to $\lambda/2n$, where λ is a wavelength of the excitation light and n is a refractive index of the sample.

[0013] According to another aspect of the invention, said average size S of the speckle grain of the scattering sample may be computed by measures of sample image intensity autocorrelation, as a function of distance.

[0014] According to a further aspect of the invention, the method may comprise a step for de-magnifying the coherent excitation light beam, before step A.

[0015] It is another specific subject-matter of the present invention a fluorescence microscopy apparatus comprising a wavefront modulation unit, configured to receive and to amplitude and/or phase modulate a coherent excitation light beam, the apparatus being configured to illuminate a sample by the coherent excitation light beam modulated by the wavefront modulation unit, wherein the apparatus further comprises an imaging unit, configured to receive and acquire a fluorescent beam emitted from the sample, and a control unit connected to the wavefront modulation unit and to the imaging unit, wherein the apparatus is configured to implement the fluorescence microscopy method described above, thereby the control unit is configured to control the wavefront modulation unit according to step D, based on the fluorescent beam acquired by the imaging unit.

[0016] According to another aspect of the invention, said wavefront modulation unit may be a Digital Micromirror Device, DMD.

[0017] According to a further aspect of the invention, the apparatus may be configured to implement the method described above, comprising a coherent excitation light beam de-magnifying unit.

[0018] The method according to the present invention

uses optimization algorithms to shape an amplitude and phase configuration of an excitation coherent light beam wavefront, in order to maximize the fluorescent signal emitted by an emitter located on a surface or embedded into a sample. In the following of the description reference will be indifferently made to optimization and shaping of the amplitude and phase configuration of a light beam wavefront, meaning one or more variation in amplitude and/or phase of the wavefront aimed to maximise a fluorescence signal emitted by an emitter.

[0019] The signal enhancement is due to an enhancement of the light intensity of a speckle grain, which is located at the target emitter (enhanced speckle grain).

[0020] In the description and the attached claims, reference will be made to *speckle* meaning a dotted figure obtained as a coherent light wave is reflected by a scattering media and a *speckle* grain is an intensity maximum, which is located in the *speckle* field. Once the optimization is completed, the signal of the speckle grain (obtained by subtracting the non-optimized fluorescence to the optimized image) is super-localized by a Gaussian fit of the data. By generating multiple foci, i.e. enhanced speckle grains, across the field of view and aggregating the information from all the contributions, a complete image of the sample is reconstructed.

[0021] The advantages of the method according to the invention over the prior art solutions are numerous and significant.

[0022] The method according to the present invention relies on the fact that the size of an excitation light beam focus, i.e. a light focus, obtained by shaping an amplitude and phase configuration of the wavefront close or inside a scattering sample, is not limited by the illumination and collection optics numerical aperture NA, but is defined by the size of the enhanced speckle grain of the sample. In other words, it is obtained a light focus whose size, after shaping the amplitude and phase configuration of the wavefront, is equal to those of the speckle grain. Hence the independence of spatial resolution from the illumination / collection optics of the microscopy apparatus. The average size S of a speckle grain is equal to a $\lambda/2n$ as disclose in Goodman, N. W. "Speckle phenomena in optics: theory and applications" (Roberts and Company Publishers, 2007), where λ is the wavelength of the incident light and n is the refraction index of the media. Recently, the size S of a speckle grain at the surface of a high scattering media was measured to be less than 100 nanometer, as shown in Park, N.-H. et al. "Sub-wavelength light focusing using random nanoparticles." Nature photonics 7, 454-458 (2013) and in Van Putten, E. et al. "Scattering lens resolves sub-100 nm structures with visible light." Physical review letters 106, 193905 (2011).

[0023] In other words, the limiting numerical aperture for the method according to the invention is the one defined by k-vectors generated by the sample through the scattering rather than those defined by the illumination and collection optics. This allows advantageously

achieving a sub-diffraction resolution a scattering sample, larger up to six time the theoretical diffraction limit.

[0024] A second advantageous aspect of the method according to the invention is that, as the resolution is independent of the microscopy apparatus optics, the method according to the invention allows working with optics having long work distance and then not directly connected to the investigated samples. In other words, the control of the light scattered by a sample can be a powerful tool to increase the resolution, especially in those cases where a high resolution is required together with a long working distance. Moreover, to implement the method it is possible to exploits quite simply experimental setup by combining features common in most optical microscopes, such as photo cameras and interference filters, with a spatial light modulator. This, advantageously, makes the method extremely versatile as it can be applied to any fluorescent imaging system.

[0025] Finally, as the method according to the invention allows obtaining high resolution without the need of high power light source, a further advantage is that of being able to use it to investigate samples with low damage thresholds, and it may be easily implemented to in vivo investigation of sensible tissues such as human retina.

[0026] The present invention will be now described, by way of illustration and not by way of limitation, according to its preferred embodiments, by particularly referring to the Figures of the annexed drawings, in which:

Figure 1 shows a schematic of (a) preferred embodiment of an apparatus configured to implement the method according to the invention, (b) a schematic representing optics driven resolution limit in a standard microscopy apparatus, and (c) schematic representing a resolution limit depending on the size S of a speckle grain obtained by the method according to the invention;

Figure 2 shows the sizes of a focus of an excitation the size of an excitation coherent light beam focus impinging a polished glass surface (Figure 2a) and a known scattering medium (Figure 2b) respectively, experimentally obtained implementing a shaping the amplitude and phase configuration of the excitation light beam wavefront of a preferred embodiment of the method according to the invention, the related intensity profiles (Figure 2c) and the related beam waist values as a function of the numerical aperture NA;

Figure 3 schematically shows some steps of the preferred embodiment of the method implemented by the apparatus of Figure 1 to obtain high-resolution images of a first known scattering sample;

Figure 4 shows images (a), (d) and (g) of a second known scattering sample obtained by a standard fluorescence microscopy method varying the numerical aperture NA of the collection optics and the corresponding images (b), (e), and (h) obtained by the

preferred embodiment of the method of Figures 2 and 3, and compares the different intensity profile (c), (f) and (i) along a same dashed line;

Figure 5 shows images of a biological sample obtained by a standard fluorescence microscopy method (Figures 5l e 5m) and by the preferred embodiment of the method implemented by the apparatus of Figure 1 and illustrated in Figure 3 (Figure 5n); Figure 6 shows autocorrelation graphs as a function of distance of the scattering sample already shown in the images of Figure 4 and f the biological sample already shown in the images of Figure 5 respectively.

[0027] Referring to Figure 1a, an apparatus 100 configured to implement the method according to the invention comprises a source (not shown in Figure 1) emitting an exciting coherent light beam 5 with a wavelength λ such as to excite fluorescent emitters in a sample 20, for example a monochromatic laser beam, optionally with a 532 nanometer (nm) wavelength. The apparatus 100 further comprises a demagnification unit not shown in figure to demagnify the beam 5, such as for example a Galilean telescope comprising two lenses with a focal ratio f_1/f_2 that is equal to demagnification. The apparatus 100 comprising a unit 10 of modulation of amplitude and/or phase configuration of a light beam wavefront, configured to receive and modulate in amplitude and/or phase the excitation coherent light beam 5.

[0028] In the preferred embodiment of the apparatus 100, such a unit 10 of modulation of amplitude and/or phase configuration of a light beam wavefront is a Digital Micromirror Device DMD. Other embodiments of the present invention may include different units 10 of modulation of amplitude and/or phase configuration of a light beam wavefront such as for example light spatial modulator and deformable mirrors. Downstream of the unit 10 of modulation, following the path of the light beam 5 from the source to the sample 20, the apparatus 100 comprises a lens 25 and an optical objective 30, that may also be a simple lens, for focusing the modulated excitation coherent light beam 5 coming out from the unit 10 of modulation on the sample 20. Moreover, the optical objective 30 collects the light coming from the sample 20, including a fluorescent emitted component (i.e. a fluorescent beam emitted by the sample 20) and a reflected component of the exciting light beam 5. The numerical aperture NA of the optical objective 30 is controlled through a diaphragm 35. The apparatus 100 further comprises a beam splitter driven the light coming out from the sample towards an imaging unit 45, such as for example a CMOS or CCD camera. A spectral filter 50 removes the reflected component of the exciting light beam 5 from the light coming out from the sample, so that only the fluorescence emitted component reaches the imaging unit 45 after passing through an optical group 55, for example an eyepiece. In the preferred embodiment of the present invention, the spectral filter 50 is an interference filter. A control unit 60 is connected to the unit 10

of modulation of amplitude and/or phase configuration of a light beam wavefront and to the imaging unit 45. Such a control unit 60 master the unit 10 of modulation of amplitude and/or phase configuration of the wavefront depending on the images obtained from the imaging unit 45, i.e. through a feedback loop, as will be described in the following in particular relating to Figures 2 and 3.

[0029] Figures 1b and 1c, show a schematic of the principle underlying the method according to the invention. While the microscope resolution is usually determined by the focusing/collection optics (Figure 1b), the signal of a fluorescent emitter into a scattering sample may be exploited to overcome the collection optics limitation. In such a case the resolution is limited by the size S of the speckle gain on the surface of the sample (Figure 1c).

[0030] For the sake of simplicity, in the following description and in the claims we will use the term "configuration" of a wavefront meaning an amplitude and phase configuration of a wavefront, wherein the amplitude and / or phase may be modulated or not.

[0031] In the method according to the invention, an excitation light beam 5 wavefront with a first initial configuration C^1 not modulated impinges the sample 20, and a first initial image F^1 , or background *frame* $F^1 = F_B$, of the sample 20 is acquired by the imaging unit 45. An interest area of the image formed by the unit 45 where there are fluorescent signals, inside which M pixels P_N are chosen, with $N = 1, \dots, M$, whose coordinates xy on an image plane are $[x_i, y_i]$.

[0032] Next, an optimization step of the configuration of the wavefront of the excitation light beam 5 is implemented, to maximize the fluorescent signal coming from the surface of the sample 20 generating an enhanced speckle grain. Recently, optimization algorithm of the wavefront has been implemented to focus the light on a single grain of a disordered speckle scheme, as shown for example by papers of Vellekoop, I. M., et al. "Exploiting disorder for perfect focusing." Nature photonics 4, 320-322 (2010), of Vellekoop, I. M. et al. "Focusing coherent light through opaque strongly scattering media." Optics letters 32, 2309-2311 (2007), and of Di Battista, D., et al. "Enhanced adaptive focusing through semi-transparent media." Scientific reports 5, 17406 (2015). A light focus obtained by such algorithms is made through constructive interferences by many different optical paths, shaping the configuration of the excitation light beam wavefront, i.e. handling the phase or the amplitude of the excitation beam wavefront, by spatial light modulator such as micromirror digital devices by a feedback loop, as shown for example by papers of Vellekoop, I. & Mosk, A. "Phase control algorithms for focusing light through turbid media." Optics communications 281, 3071-3080 (2008) and of Akbulut, D. et al. "Focusing light through random photonic media by binary amplitude modulation." Optics express 19, 4017-4029 (2011). In the preferred embodiment of the method according to the invention, the optimization of the wavefront of the excitation light beam comprises a preliminary step of de-

magnification of the beam 5 in such a way to illuminate an active area of the DMD unit 10 of modulation of a surface homogenously. In other words, the sample is illuminated by a demagnified image of the DMD unit 10 of modulation illuminated by the beam 5. Next, one of the M pixels, P_N with $N = 1 \dots M$, is chosen as target pixel and the configuration of the wavefront impinging the sample 20 is varied by the unit 10 of modulation until maximize the intensity of a fluorescent signal related to the pixel as detailed described in the following.

[0033] The first initial image F^1 is set as a target pixel P_N reference image F^{ref} , a target pixel P_N first intensity $I_{P_N}^1$ of the first initial image F^1 is set as a target pixel P_N reference intensity $I_{P_N}^{ref}$ and the first initial configuration C^1 of the wavefront is set as a reference configuration $C^1 = C^{ref}$. The DMD unit 10 of modulation is assembled in $p \times q$ segments or micromirrors, each one being able to assume an orientation between a plurality of $V=2$ orientations. In further embodiments of the invention, each micromirror can assume more than two orientation, i.e. $V \geq 2$. The orientation of a randomly chosen micromirror m of DMD is varied so that the wavefront impinging the sample assumes a second configuration C^2 different from the first one $C^2 \neq C^1$ and a second image F^2 is acquired. A target pixel P_N second intensity $I_{P_N}^2$ of the second image F^2 is compared to the target pixel P_N reference intensity $I_{P_N}^{ref}$. If the second intensity $I_{P_N}^2$ is larger than the reference intensity $I_{P_N}^{ref}$, the orientation variation of the micromirror m , and therefore the second configuration of the wavefront, is accepted. Thus, we assume as the reference intensity the greater intensity between them, namely $I_{P_N}^{ref} = I_{P_N}^2$, as the reference configuration of the wavefront the one for which we have the greater intensity, namely $C^{ref} = C^2$, and as reference image the image where the target pixel P_N intensity is larger, namely $F^{ref} = F^2$. If the second intensity $I_{P_N}^2$ is less than the reference intensity $I_{P_N}^{ref}$, the variation is not accepted and the previous orientation of the micromirror m , and therefore the previous configuration of wavefront, is restored. In the latter case, the reference intensity and the reference configuration remain unchanged, together with the reference image.

[0034] Subsequently, the orientation of a randomly chosen micromirror n , with $n \neq m$, is varied so that the wavefront impinging the sample assumes a third configuration C^3 and a third image F^3 is acquired. A target pixel P_N third intensity $I_{P_N}^3$ of the third image F^3 is compared to the reference intensity $I_{P_N}^{ref}$. If the third intensity $I_{P_N}^3$ is larger than the reference intensity $I_{P_N}^{ref}$, the orientation variation of the micromirror n , and therefore the third configuration C^3 of the wavefront, is accepted. Thus, we assume as the reference intensity the greater intensity between them, namely $I_{P_N}^{ref} = I_{P_N}^3$, as the reference configuration of the wavefront the one for which we have the greater intensity, namely $C^{ref} = C^3$, and as reference image the image where the target pixel P_N intensity is larger, namely $F^{ref} = F^3$. If the third intensity $I_{P_N}^3$ is less than the reference intensity $I_{P_N}^{ref}$, the variation is not accepted

and the previous orientation of the micromirror n , and therefore the previous configuration of wavefront, is restored. In the latter case, the reference intensity and the reference configuration remain unchanged.

5 The above-described procedure is repeated for a number Q of micromirrors of the DMD unit 10 of modulation for each target pixel of the area of interest (namely, for each one of the M target pixel P_N). In the preferred embodiment of the method, Q is greater than or equal to 60. Overall, for each target pixel, $V \times Q$ configurations of the excitation light beam wavefront impinges on the sample.

[0035] The step of optimization of the configurations of wavefront decreases the size S of a speckle grain of a scattering sample image, obtaining a reduced size speckle grain, and make it independent of the optical aperture of the focusing optics.

[0036] The inventors have carried out an experiment to observe the coherent light scattered by a not scattering sample and that scattered by a scattering sample. The experiment has been carried out using the apparatus of Figure 1 without the spectral filter 50 and with the diaphragm 35 placed before the beam splitter 40 so as not to influence the resolution of the collection optics.

[0037] Figure 2 shows the images of focus of an excitation coherent light beam 5 obtained at the end of the above described optimization step of the configuration of the wavefront on a not scattering sample and on a scattering sample. In particular, for a same value, equal to 0.03, of the numerical aperture NA of the focusing optics, determined by the diaphragm 35, Figure 2a shows an image of the light focus obtained on a sample of polished glass (not scattering sample), while figure 2b shows an image of the light focus obtained on a 60 μm thick layer of commercial TiO_2 titanium dioxide (Product 224227 by SIGMA ALDRICH) prepared in a suspension of ethanol and deposited on a slide (scattering sample). The layer thickness has been adjusted exploiting a feeler gauge.

[0038] It can be observed that the average size S of a speckle grain of the scattering sample is about $\lambda/2n = 150 \text{ nm}$. The optimization of the configuration of wavefront was performed using a DMD Vialux discovery 4100 divided into 11×11 square segments each with a side size of 70 micrometers (μm). In the experiment, the exposure time for each configuration of wavefront on a target pixel, ranges from 2 to 40 microseconds (μs), and the step of optimization of the configuration of wavefront was performed for 60 micromirrors for each target pixel. Figs. 2a and 2b show that the size of a light focus, obtained by step of optimization of the configuration of wavefront, on a smooth surface is much larger than the size obtained on a scattering surface. Figure 2c shows the intensity profiles, in arbitrary units, of the light focus of Figure 2a (solid dot) and of the light focus of Figure 2b (empty dots), from which the excitation light beam 5 measured waist (MW) values are obtained, by Gaussian fit (continuous lines), equal to 5,95 on the polished glass sample and 1,45 on the scattering sample, with respect

to a same theoretical waist (TW) of 5,7.

In addition, the inventors carried out the same experiment when the numerical aperture NA of the apparatus varied, adjusting the diameter D of the diaphragm. Figure 2d shows the sizes in micrometers (μm) of the waist of the beam 5 on the polished glass sample and on the scattering sample as a function of the diameter D of the diaphragm and they have been compared with the expected theoretical values (continuous line). It is evident that the size of the light focus on the scattering sample is independent of the numerical aperture NA.

[0039] At the end of the optimization step of the configuration of wavefront, a final image $F^{fin}(I_{PN}^{max})$ is obtained with a local maximum fluorescence emission for the target pixel P_N inside the area of interest, where I_{PN}^{max} is just the maximum intensity in the target pixel P_N obtained at the end of the optimization step of the configuration of wavefront, due to the configuration of wavefront determined at the end of the optimization.

[0040] Subsequently, the method continues with a step of subtraction of the background image F_B , previously obtained with the unmodulated excitation light beam, optionally demagnified, from the final image $F^{fin}(I_{PN}^{max})$ obtained from the step of optimization of the configuration of wavefront, so as to obtain an image $F_{speckle(PN)}$ containing only light generated (i.e. containing exclusively fluorescence signals coming) from an underlying speckle grain, namely contained in the pixel $[X_N, Y_N]$, with intensity $I_{PN}^{speckle}$. In other words, an image of the sample is obtained in which there is a single illuminated spot, corresponding to an optimized speckle, namely a speckle with intensity larger than the surrounding speckle intensities. The underlying speckle grain appears on the imaging unit 45 with a size larger than its real extension due to the limited optical resolution of the collection optics that makes a convolution (see the image of Figure 3a).

[0041] Next, the speckle grain is superlocalized, i.e. the coordinates (X_N, Y_N) in a xy plane and the intensity I_N of the final corresponding light focus are optimized in a localization step by a fit with a Gaussian function with free center coordinates. At the end of the localization step an F_N image is reconstructed containing a Gaussian intensity distribution with center coordinates (X_{fN}, Y_{fN}) , intensity I_{fN} and waist equal to the average size S of the speckle grain at optimized resolution in the sample. Therefore, knowledge of the size S of a speckle grain of a scattering sample is necessary to obtain the final high-resolution image of the method according to the invention. This size can be derived from the formula $S=\lambda/n$ or can be calculated experimentally, for example from the autocorrelation of the intensity of G acquired images of speckle grains as a function of distance (as will be described later in relation to Figure 6).

[0042] The steps of optimization of the configuration of wavefront, of subtraction, and of localization and reconstruction are then repeated for each one of the M target pixels belonging to the selected area.

[0043] Figure 3 shows the images resulting from the

above-described steps of the method. Figures (c₁) (with a detail portion shown in (a)), (c₂), and (c₃) show images of the scattering sample with three different local maxima, obtained with the optimization step of the configuration of wavefront of the preferred embodiment of the method, for three different target pixels. Figures (d_i) (with a detail portion shown in (b)), (d₂), and (d₃) show images reconstructed from the steps of subtraction of the background image from the corresponding images (c₁), (c₂), and (c₃) and of localization by a Gaussian fit. The above-mentioned steps of the method are figuratively sketched in the central diagram of Figure 3, in which the axis orthogonal to the plane xy represents the index N of the target pixel P_N . The final high resolution image (f) of the scattering sample is obtained in the last step of the method in which all the information obtained from the N reconstructed images are reported in a single image. For comparison, it is also shown the image (e) obtained by summing the images of the optimized light foci with different configurations of the unit 10 of modulation, but not superlocalized, as well as the intensity profiles (g) and (h) of the images (e) and (f) along a line.

[0044] In the preferred embodiment of the method, the steps of optimizing, subtracting and localizing are implemented in sequence for each pixel N. In other embodiments, the optimization steps can be performed for each pixel N, then the steps of subtraction and localization can be implemented on each image outgoing the optimization steps, or the subtraction steps can be implemented on each image outgoing the optimization steps and then the localization steps can be implemented for each image resulting from the subtraction steps.

[0045] The inventors of the present invention have carried out experiments which have demonstrated the reliability of the preferred embodiment of the method described in relation to Figure 3, using the apparatus of Figure 1. Figure 4 shows the results of a first experiment on two commercial fluorescent beads (0.5 μm in diameter, Spherotech FP-00556-2) seated on a sample of a layer of titanium dioxide (used in the experiment previously described with reference to Figure 2). Figure 4a shows a first image acquired with a low numerical aperture NA and low optical resolution r equal to about 1.3 μm without applying the method according to the invention. Figure 4b shows the corresponding reconstructed image obtained by applying the method according to the present invention with the same numerical aperture NA of the objective. In the image of Figure 4a, the two fluorescent beads appear as a single elongated structure, by contrast the reconstructed image of Figure 4b the two fluorescent beads appear separate and clearly distinguishes. Figure 4c illustrates intensity profiles along a same dashed line / shown along the two fluorescent beads of Figures 4a and 4b. From Figures 4b, 4c, a resolution of the images obtained by the method according to the invention is calculated equal to about 150 nm that is consistent with the expected size of the speckle grain in the scattering titanium dioxide sample.

[0046] By decreasing the numerical aperture NA of the objective and the optical resolution r (closing the diaphragm, the optical resolution r becomes first about 1.7 μm and then about 2.2 μm) the two fluorescent beads remain clearly distinguishable by implementing the method according to the invention, as shown by the images of figures 4e and 4h and by the relative intensity profiles on the dashed line I of figures 4f and 4i. For comparison, the images acquired with the same numerical apertures without implementing the method are shown in figures 4d and 4g and the relative profiles on the same dashed line I are shown in figures 4f and 4i.

[0047] To demonstrate the feasibility of the method according to the present invention on standard semi-transparent biological systems, the inventors carried out a second experiment on brain slices derived from a mouse affected by Alzheimer's disease (3xTg-AD) to detect the presence of plaques of Amyloid Beta, whose signal was detected using a secondary antibody conjugated with *Nile red*. The samples of animal origin were obtained in accordance with the European directive 2010/63/EU and with the related Italian legislative implementation decree n. 26 of 04.03.2014. High resolution (obtained with a 0,75 NA objective) and low resolution (obtained by reducing NA to 0,21) images, and the images reconstructed implementing the method at low resolution (i.e. NA equal at 0,21), are shown respectively in Figure 5l, 5m and 5n.

[0048] The inventors have calculated a 200 nm resolution (consistent with the measured size S of the speckle grain in the sample), corresponding to an increase of six times compared to the theoretical resolution given by the collection optics. In the experiments whose results were reported in Figures 4 and 5, calculated values of the size S of a speckle grain of the scattering samples were used. The inventors collected $G = 100$ images of speckle grains for a layer of TiO_2 (equal to that shown in the images of Figure 4) and a slice of 250 μm of mouse brain affected by Alzheimer's disease (equal to that shown in the images of Figure 5). They calculated the autocorrelations of the intensities as a function of distance, whose graphs are shown in Figures 6a and 6b respectively. Through a Gaussian fit of the central maxima of the autocorrelation functions, the values of the size S of the speckle grains were obtained, respectively equal to $S_{\text{TiO}_2} = 146 \pm 3 \text{ nm}$ and $S_{\text{brain}} = 195 \pm 7 \text{ nm}$.

[0049] In the foregoing the preferred embodiments have been described and variants have been suggested of the present invention, but it should be understood that those skilled in the art can make variations and changes, without so departing from the scope of protection thereof, as defined by the attached claims.

Claims

1. Fluorescence microscopy method comprising the following steps:

A. illuminating a scattering sample including one or more fluorescent emitters with a coherent excitation light beam (5) having a wavefront with a first initial configuration C^1 for exciting said one or more fluorescent emitters comprised in the scattering sample;

B. acquiring a first initial image F^1 corresponding to a background image $F^1 = F_B$ of the scattering sample, through a pixel imaging unit (45), obtaining a speckle grain image;

C. selecting M target pixels P_N , with $N = 1, \dots, M$, of coordinates $[x_N, y_N]$ belonging to an area of the first initial image F^1 having fluorescence signals of at least one fluorescent emitter, each one of the M target pixels P_N having a first initial intensity $I_{P_N}^1$;

D. optimising the first initial configuration of the wavefront for each one of the M target pixels P_N , for decreasing the speckle grain size of the first initial image F^1 and obtaining a final image $F^{fin}(I_{P_N}^{max})$ of the scattering sample with a local maximum $I_{P_N}^{max}$ of the fluorescence signal corresponding to a maximum intensity of the target pixels P_N ;

E. subtracting the first initial image F_B of background, obtained at step B, from the final image $F^{fin}(I_{P_N}^{max})$, obtained at step D, for each one of the M target pixels P_N , obtaining an image $F_{\text{speckle}(P_N)}$ having only fluorescent signals coming from a speckle grain located at pixel $[x_N, y_N]$ with intensity $I_{P_N}^{\text{speckle}}$, for each one of the M target pixels P_N ;

F. fitting the image $F_{\text{speckle}(P_N)}$, obtained at step E, with a Gaussian function with free center coordinates, for each one of the M target pixels P_N , thereby obtaining coordinates (X_N, Y_N) and intensity I_N in a xy plane;

G. generating an image F_N containing a Gaussian distribution centered at coordinates (X_N, Y_N) and with intensity I_N , obtained at step F, and with a waist equal to an average size S of speckle grain of the scattering sample, for each one of the M target pixels P_N ;

H. generating a final image of the sample by summing the M images F_N obtained at step G, for each one of the M target pixels P_N .

2. Microscopy method according to claim 1, wherein step D comprises, for each one of the M target pixels P_N , the following sub-steps:

D.1 - set the first initial configuration C^1 of the wavefront as a reference configuration $C^1 = C^{ref}$ of the wavefront, the first initial image F^1 as a reference image $F^1 = F^{ref}$, and a first intensity $I_{P_N}^1$ at the target pixel P_N of the first initial image F^1 as a reference intensity $I_{P_N}^1 = I_{P_N}^{ref}$ at the target pixel P_N ;

D.2 - repeating T times, with $T > 1$, the following cycle of substeps:

D.2.1 - varying the reference configuration C^{ref} of the wavefront through an amplitude and/or phase modulation unit (10) so as to obtain an i-th configuration C^i of the wavefront;

D.2.2 - acquiring an i-th image F^i with an i-th intensity I_{PN}^i at the target pixel P_N ;

D.2.3 - checking whether the i-th intensity I_{PN}^i value at the target pixel P_N is greater than the reference intensity I_{PN}^{ref} thereby:

if $I_{PN}^i > I_{PN}^{ref}$, then the i-th configuration C^i of the wavefront obtained at step D.2.1 is accepted as the reference configuration C^{ref} of the wavefront, i.e. $C^{ref} = C^i$, and $F^{ref} = F^i$ and $I_{PN}^{ref} = I_{PN}^i$ are set, else

if $I_{PN}^i < I_{PN}^{ref}$, then the i-th configuration C^i of the wavefront obtained at step D.2.1 is not accepted, and the reference configuration C^{ref} of the wavefront before the variation performed at step D.2.1 is restored;

D.3 - setting the reference image F^{ref} as the final image $F^{ref} = F^{fin}(I_{PN}^{max})$ and the reference intensity I_{PN}^{ref} as a local maximum I_{PN}^{max} of fluorescence signal at the target pixel P_N .

3. Microscopy method according to claim 2, wherein the amplitude and/or phase modulation unit (10) is a digital micromirror device (10) comprising a $p \times q$ matrix of micromirrors and the step D.2.1 is implemented by varying the orientation of $Q \geq 1$ micromirrors of the digital micromirror device (10), thereby $Q \leq p \times q$, wherein each micromirror can take on $V > 2$ orientations, so that $T = V \times Q$.
4. Microscopy method according to any one of preceding claims, wherein the average size S of the speckle grain of the scattering sample is set equal to $\lambda/2n$, where λ is a wavelength of the excitation light and n is a refractive index of the sample.
5. Microscopy method according to any one of preceding claims 1 to 3, wherein the average size S of the speckle grain of the scattering sample is computed by measures of sample image intensity autocorrelation, as a function of distance.
6. Microscopy method according to any one of preceding claims, comprising a step for de-magnifying the coherent excitation light beam (5), before step A.
7. Fluorescence microscopy apparatus (100) compris-

ing a wavefront modulation unit (10), configured to receive and to amplitude and/or phase modulate a coherent excitation light beam (5), the apparatus (100) being configured to illuminate a sample (20) by the coherent excitation light beam modulated by the wavefront modulation unit (10), wherein the apparatus (100) further comprises an imaging unit (45), configured to receive and acquire a fluorescent beam emitted from the sample (20), and a control unit (60) connected to the wavefront modulation unit (10) and to the imaging unit (45), wherein the apparatus (100) is configured to implement the fluorescence microscopy method according to any one of the claims 1 to 6, whereby the control unit (60) is configured to control the wavefront modulation unit (10) according to step D, based on the fluorescent beam acquired by the imaging unit (45).

8. Fluorescence microscopy apparatus (100) according to claim 7, wherein the wavefront modulation unit (10) is a Digital Micromirror Device, DMD.

9. Fluorescence microscopy apparatus (100) according to claim 7 or 8 configured to implement the method according to claim 6, comprising a coherent excitation light beam (5) de-magnifying unit.

Patentansprüche

1. Fluoreszenzmikroskopieverfahren, das die folgenden Schritte umfasst:

A. Beleuchten einer Streuprobe, die einen oder mehrere Fluoreszenzemitter enthält, mit einem kohärenten Anregungslichtstrahl (5), der eine Wellenfront mit einer ersten Ausgangskonfiguration C^1 hat, zum Anregen des einen oder der mehreren Fluoreszenzemitter, der bzw. die in der Streuprobe enthalten ist bzw. sind;

B. Gewinnen eines ersten anfänglichen Bildes F^1 , welches einem Hintergrundbild $F^1 = F_B$ der Streuprobe entspricht, durch eine Pixelabbildungseinheit (45), wodurch ein Speckle-Korn-Bild (speckle grain image) erhalten wird;

C. Auswählen von M Zielpixeln P_N , mit $N = 1, \dots, M$, aus Koordinaten $[x_N, y_N]$, die zu einem Bereich des ersten anfänglichen Bildes F^1 gehören, der Fluoreszenzsignale mindestens eines Fluoreszenzemitters enthält, wobei ein jeder der M Zielpixel P_N mindestens eine erste anfängliche Intensität I_{PN}^1 aufweist;

D. Optimieren der ersten anfänglichen Konfiguration der Wellenfront für einen jeden der M Zielpixel P_N , um die Speckle-Korn-Größe des ersten anfänglichen Bildes F^1 zu verringern und ein finales Bild $F^{fin}(I_{PN}^{max})$ der Streuprobe zu erhalten, mit einem lokalen Maximum I_{PN}^{max} des Flu-

- oreszenzsignals, welches einer maximalen Intensität der Targetpixel P_N entspricht;
- E. Subtrahieren des ersten anfänglichen Bildes F_B des Hintergrunds, welches im Schritt B erhalten wurde, von dem finalen Bild $F^{fin}(I_{PN}^{max})$, welches in Schritt D erhalten wurde, für einen jeden der M Zielpixel P_N , wodurch ein Bild $F_{speckle(PN)}$ erhalten wird, welches nur Fluoreszenzsignale enthält, welche aus einem Speckle-Korn kommen, welches sich an Pixel $[x_N, y_N]$ befindet, mit einer Intensität $I_{PN}^{speckle}$, für einen jeden der M Zielpixel P_N ;
- F. Fitten des Bildes $F_{speckle(PN)}$, welches in Schritt E erhalten wurde, mit einer Gaußfunktion mit freien Mittelkoordinaten, für einen jeden der M Zielpixel P_N , wodurch Koordinaten (X_N, Y_N) und eine Intensität I_N in einer xy-Ebene erhalten werden;
- G. Erzeugen eines Bildes F_N , welches eine Gaußverteilung enthält, die an Koordinaten (X_N, Y_N) zentriert ist und mit einer Intensität I_N , die in Schritt F erhalten wurde, mit einer Breite (waist), die gleich einer durchschnittlichen Größe S eines Speckle-Korns in der Streuprobe ist, für einen jeden der M Zielpixel P_N ;
- H. Erzeugen eines finalen Bildes der Probe, in dem die M in Schritt G erhaltenen Bilder F_N für einen jeden der M Zielpixel P_N summiert werden.
2. Mikroskopieverfahren nach Anspruch 1, wobei der Schritt D für einen jeden der M Zielpixel P_N , die folgenden Unterschritte enthält:
- D.1 - Ansetzen der ersten anfänglichen Konfiguration C^1 der Wellenfront als eine Referenzkonfiguration $C^1 = C^{ref}$ der Wellenfront, des ersten anfänglichen Bildes F^1 als ein Referenzbild $F^1 = F^{ref}$, und einer ersten Intensität I_{PN}^1 an dem Zielpixel P_N des ersten anfänglichen Bildes F^1 als eine Referenz-Identität $I_{PN}^1 = I_{PN}^{ref}$ an dem Targetpixel P_N ;
- D.2 - T-faches wiederholen, mit $T > 1$, des folgenden Zyklus aus Unterschritten:
- D.2.1 - Variieren der Referenzkonfiguration C^{ref} der Wellenfront durch eine Amplituden- und/oder Phasenmodulationseinheit (10), um eine i-te Konfiguration C^i der Wellenfront zu erhalten;
- D.2.2 - Gewinnen eines i-ten Bildes F^i mit einer i-ten Intensität I_{PN}^i an dem Zielpixel P_N ;
- D.2.3 - Prüfen, ob der i-te Intensitätswert I_{PN}^i an dem Zielpixel P_N größer ist, als die Referenzintensität I_{PN}^{ref} , wobei: wenn $I_{PN}^i > I_{PN}^{ref}$, dann wird die i-te Konfiguration C^i der Wellenfront, die in

Schritt D.2.1 erhalten wurde, als die Referenzkonfiguration C^{ref} der Wellenfront akzeptiert, das heißt $C^{ref} = C^i$, und $F^{ref} = F^i$ und $I_{PN}^{ref} = I_{PN}^i$ werden angesetzt, und ansonsten wenn $I_{PN}^i < I_{PN}^{ref}$, dann wird die i-te Konfiguration C^i der in Schritt D.2.1 erhaltenen Konfiguration C^{ref} der Wellenfront nicht akzeptiert, und die Referenzkonfiguration C^{ref} der Wellenfront vor der in Schritt D.2.1 durchgeführten Variation, wird restauriert bzw. beibehalten;

D.3 - Ansetzen des Referenzbildes F^{ref} als finales Bild $F^{ref} = F^{fin}(I_{PN}^{max})$ und der Referenzintensität I_{PN}^{ref} als ein lokales Maximum I_{PN}^{max} des Fluoreszenzsignals am Zielpixel P_N .

3. Mikroskopieverfahren nach Anspruch 2, wobei die Amplituden- und/oder Phasenmodulationseinheit (10) eine digitale Mikrospegeleinheit (10) ist, die eine $p \times q$ Matrix von Mikrosiegeln umfasst, und der Schritt D.2.1 implementiert wird, indem die Orientierung von $Q \geq 1$ Mikrosiegeln der digitalen Mikrospegeleinheit (10) variiert werden, wobei $Q \leq p \times q$, wobei ein jeder Mikrospiegel $V > 2$ Orientierungen annehmen kann, sodass $T = V \times Q$.
4. Mikroskopieverfahren nach einem der vorhergehenden Ansprüche, wobei die durchschnittliche Größe S des Speckle-Korns der Streuprobe gleich $\lambda/2n$ gesetzt wird, wobei λ eine Wellenlänge des Anregungslichts ist und n ein Brechungsindex der Probe.
5. Mikroskopieverfahren nach einem der vorhergehenden Ansprüche 1-3, wobei die durchschnittliche Größe S des Speckle-Korns der Streuprobe berechnet wird durch Maße einer Probenbildintensitäts-Autokorrelation als Funktion des Abstands.
6. Mikroskopieverfahren nach einem der vorhergehenden Ansprüche, umfassend einen Schritt zum Demagnifizieren des kohärenten Anregungslichtstrahls (5) vor Schritt A.
7. Fluoreszenzmikroskopievorrichtung (100) umfassend eine Wellenfront-Modulationseinheit (10), die dazu konfiguriert ist, einen kohärenten Anregungslichtstrahl (5) zu empfangen und bezüglich Amplitude und/oder Phase zu modulieren, wobei die Vorrichtung (100) dazu konfiguriert ist, eine Probe (20) durch den kohärenten Anregungslichtstrahl, der durch die Wellenfront-Modulationseinheit (10) moduliert ist, zu beleuchten, wobei die Vorrichtung (100) ferner eine Abbildungseinheit (45) umfasst, die dazu konfiguriert ist, einen Fluoreszenzstrahl zu empfangen und gewinnen, der von der Probe (20) emittiert wird, und eine Steuereinheit (60), die mit der Wellenfront-Modulationseinheit (10) und der Ab-

bildungseinheit (45) verbunden ist, wobei die Vorrichtung (100) dazu konfiguriert ist, das Fluoreszenz-Mikroskopieverfahren nach einem der Ansprüche 1-6 auszuführen, wobei die Steuereinheit (60) dazu konfiguriert ist, die Wellenfront-Modulationseinheit (10) gemäß Schritt D zu steuern, basierend auf dem von der Abbildungseinheit (45) aufgenommenen Fluoreszenzstrahl.

8. Fluoreszenzmikroskopievorrichtung (100) nach Anspruch 7, wobei die Wellenfront-Modulationseinheit (10) eine digitale Mikrospiegelvorrichtung (digital micro mirror device DMD) ist.
9. Fluoreszenzmikroskopievorrichtung (100) nach Anspruch 7 oder 8, die dazu konfiguriert ist, das Verfahren nach Anspruch 6 zu implementieren, umfassend eine De-Magnifizierungseinheit für einen kohärenten Anregungslichtstrahl (5).

Revendications

1. Procédé de microscopie à fluorescence comprenant les étapes suivantes :
 - A. éclairage d'un échantillon de diffusion comprenant un ou plusieurs émetteurs fluorescents avec un faisceau lumineux d'excitation cohérent (5) présentant un front d'onde avec une première configuration initiale C^1 pour exciter lesdits un ou plusieurs émetteurs fluorescents compris dans l'échantillon de diffusion ;
 - B. acquisition d'une première image initiale F^1 correspondant à une image de fond $F^1 = F_B$ de l'échantillon de diffusion, via une unité d'imagerie à pixels (45), obtention d'une image de grain de chatoiement (*speckle grain image*) ;
 - C. sélection de M pixels cibles P_N , avec $N = 1, \dots, M$, de coordonnées $[x_N, y_N]$ appartenant à une zone de la première image initiale F^1 présentant des signaux de fluorescence d'au moins un émetteur fluorescent, chacun des M pixels cibles P_N ayant une première intensité initiale I_{PN}^1 ;
 - D. optimisation de la première configuration initiale du front d'onde pour chacun des M pixels cibles P_N , pour diminuer la taille du grain de chatoiement de la première image initiale F^1 et obtenir une image finale $F^{fin}(I_{PN}^{max})$ de l'échantillon de diffusion avec un maximum local I_{PN}^{max} du signal de fluorescence correspondant à une intensité maximale des pixels cibles P_N ;
 - E. soustraction de la première image initiale F_B de fond, obtenue à l'étape B, depuis l'image finale $F^{fin}(I_{PN}^{max})$, obtenue à l'étape D, pour chacun des M pixels cibles P_N , obtention d'une image $F_{speckle(PN)}$ n'ayant que des signaux fluores-

cents provenant d'un grain de chatoiement situé au pixel (X_N, Y_N) d'intensité $I_{PN}^{speckle}$, pour chacun des M pixels cibles P_N ;

F. ajustement de l'image $F_{speckle(PN)}$, obtenue à l'étape E, avec une fonction gaussienne à coordonnées de centre libre, pour chacun des M pixels cibles P_N , de façon à obtenir des coordonnées (X_N, Y_N) et une intensité I_N dans un plan xy ;

G. génération d'une image F_N contenant une distribution gaussienne centrée aux coordonnées (X_N, Y_N) et d'intensité I_N , obtenue à l'étape F, et avec une taille (*waist*) égale à une taille moyenne S de grain de chatoiement de l'échantillon de diffusion, pour chacun des M pixels cibles P_N ;

H. génération d'une image finale de l'échantillon en sommant les M images F_N obtenues à l'étape G, pour chacun des M pixels cibles P_N .

2. Procédé de microscopie selon la revendication 1, où l'étape D comprend, pour chacun des M pixels cibles P_N , les sous-étapes suivantes :

D.1 - fixer la première configuration initiale C^1 du front d'onde comme configuration de référence $C^1 = C^{ref}$ du front d'onde, la première image initiale F^1 comme image de référence $F^1 = F^{ref}$, et une première intensité I_{PN}^1 au pixel cible P_N du premier image initiale F^1 comme intensité de référence $I_{PN}^1 = I_{PN}^{ref}$ au pixel cible P_N ;
 D.2 - répéter T fois, avec $T > 1$, le cycle de sous-étapes suivant :

D.2.1 - faire varier la configuration de référence C^{ref} du front d'onde grâce à une unité de modulation d'amplitude et/ou de phase (10) de manière à obtenir une i -ième configuration C^i du front d'onde ;

D.2.2 - acquisition d'une i -ième image avec une i -ième intensité I_{PN}^i au pixel cible P_N ;

D.2.3 - vérifier si la i -ième valeur d'intensité I_{PN}^i au pixel cible P_N est supérieure à l'intensité de référence I_{PN}^{ref} :

si $I_{PN}^i > I_{PN}^{ref}$, alors la i -ième configuration C^i du front d'onde obtenue à l'étape D.2.1 est acceptée comme configuration de référence C^{ref} du front d'onde, c'est-à-dire que $C^{ref} = C^i$ et $F^{ref} = F^i$ et $I_{PN}^{ref} = I_{PN}^i$ sont définis, sinon

si $I_{PN}^i < I_{PN}^{ref}$, alors la i -ième configuration C^i du front d'onde obtenue à l'étape D.2.1 n'est pas acceptée, et la configuration de référence C^{ref} du front d'onde avant la variation effectuée à l'étape D.2.1 est restituée ;

- D.3 - définir l'image de référence F^{ref} comme image finale $F^{ref}=F^{fin}(I_{PN}^{max})$ et l'intensité de référence I_{PN}^{ref} comme un maximum local I_{PN}^{max} du signal de fluorescence au pixel cible P_N .
3. Procédé de microscopie selon la revendication 2, où l'unité de modulation d'amplitude et/ou de phase (10) est un dispositif numérique à micromiroirs (10) comprenant une matrice $p \times q$ de micromiroirs et l'étape D.2.1 est mise en œuvre en faisant varier l'orientation de $Q \geq 1$ micromiroirs du dispositif numérique à micromiroirs (10), de sorte que $Q \leq p \times q$, où chaque micromiroir peut prendre des orientations $V > 2$, de sorte que $T=V \times Q$. 5
 4. Procédé de microscopie selon l'une quelconque des revendications précédentes, où la taille moyenne S du grain de chatoiement de l'échantillon de diffusion est fixée comme étant égale à $\lambda/2n$, où λ est une longueur d'onde de la lumière d'excitation et n est un indice de réfraction de l'échantillon. 10
 5. Procédé de microscopie selon l'une quelconque des revendications précédentes 1 à 3, où la taille moyenne S du grain de chatoiement de l'échantillon de diffusion est calculée par des mesures d'autocorrélation d'intensité d'image d'échantillon, en fonction de la distance. 15
 6. Procédé de microscopie selon l'une quelconque des revendications précédentes, comprenant une étape de dégrossissement du faisceau lumineux d'excitation cohérent (5), avant l'étape A. 20
 7. Appareil de microscopie à fluorescence (100) comprenant une unité de modulation de front d'onde (10), conçue pour recevoir et moduler en amplitude et/ou en phase un faisceau lumineux d'excitation cohérent (5), l'appareil (100) étant conçu pour éclairer un échantillon (20) par le faisceau lumineux d'excitation cohérent modulé par l'unité de modulation de front d'onde (10), où l'appareil (100) comprend en outre une unité d'imagerie (45), conçue pour recevoir et acquérir un faisceau fluorescent émis depuis l'échantillon (20), et une unité de commande (60) connectée à l'unité de modulation de front d'onde (10) et à l'unité d'imagerie (45), où l'appareil (100) est conçu pour mettre en œuvre le procédé de microscopie à fluorescence selon l'une quelconque des revendications 1 à 6, où l'unité de commande (60) est conçue pour commander l'unité de modulation de front d'onde (10) selon l'étape D, sur la base du faisceau fluorescent acquis par l'unité d'imagerie (45). 25
 8. Appareil de microscopie à fluorescence (100) selon la revendication 7, où l'unité de modulation de front d'onde (10) est une matrice de micromiroirs, DMD (Digital Micromirror Device). 30
 9. Appareil de microscopie à fluorescence (100) selon la revendication 7 ou 8 conçu pour mettre en œuvre le procédé selon la revendication 6, comprenant une unité de dégrossissement du faisceau lumineux d'excitation cohérent (5). 35

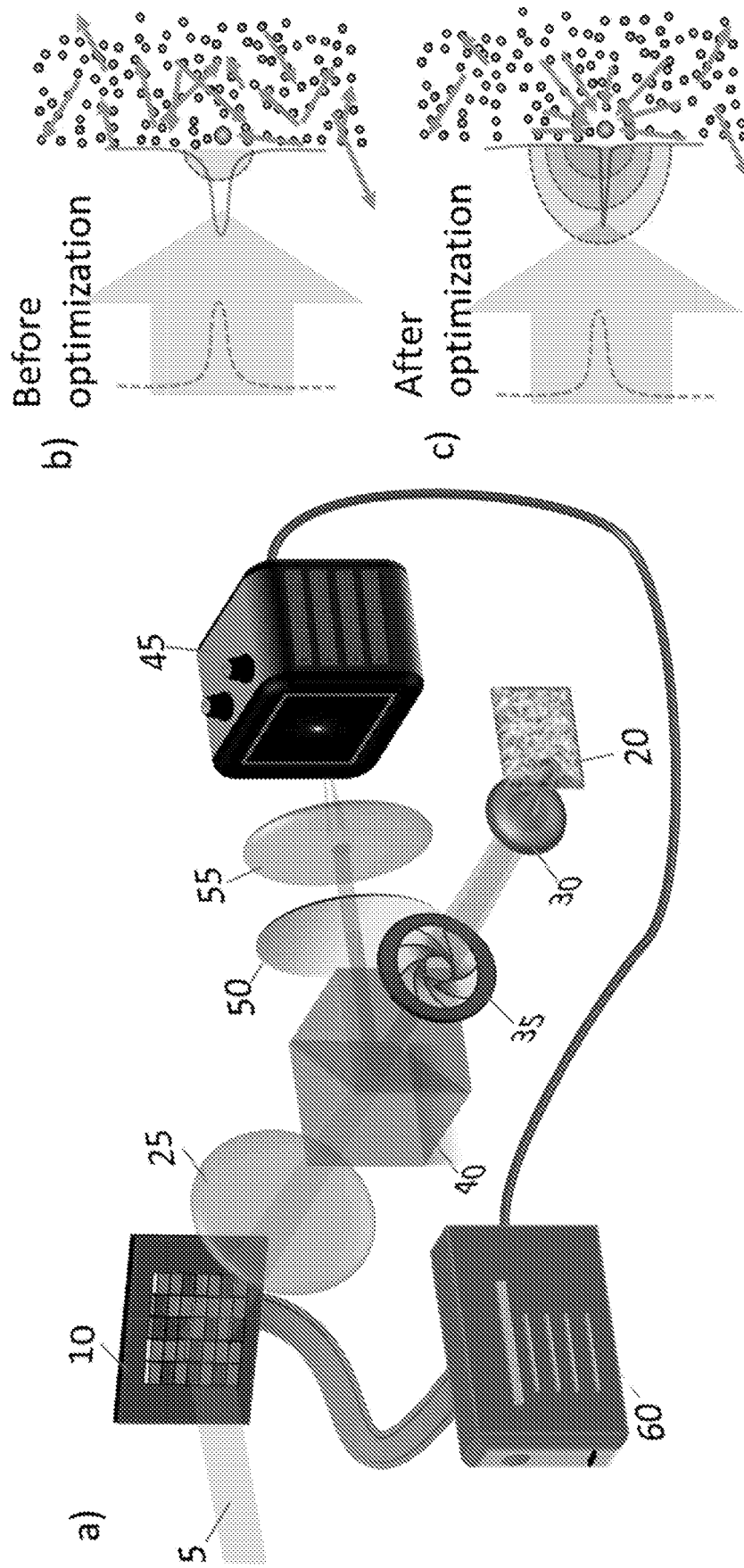


FIG. 1

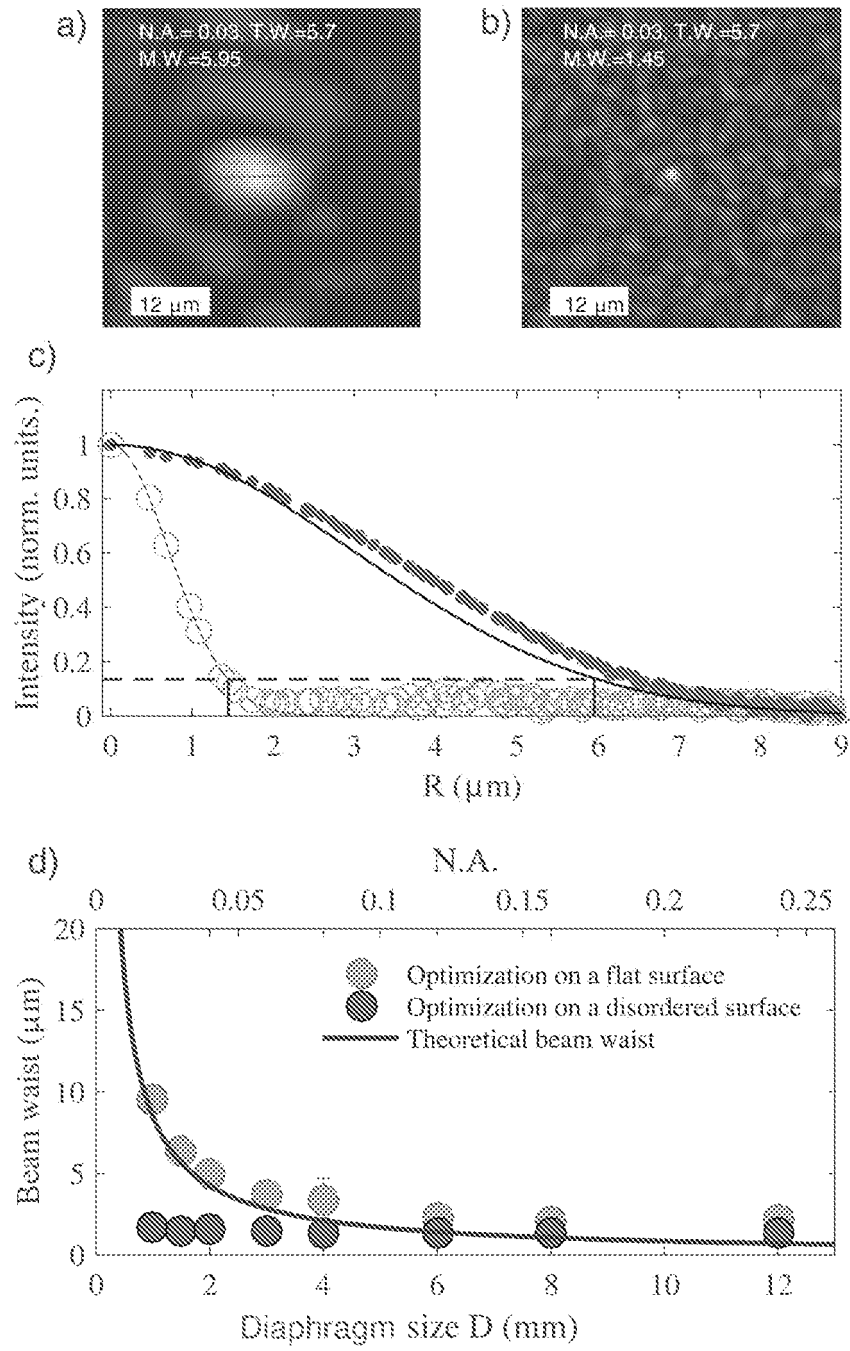


FIG. 2

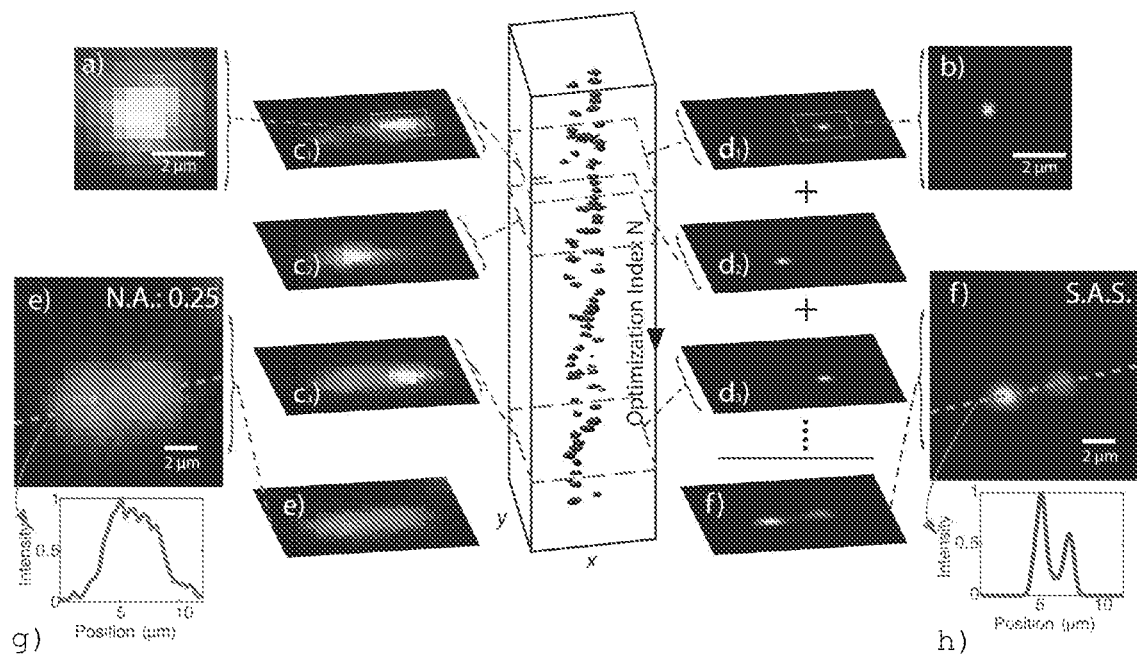


FIG. 3

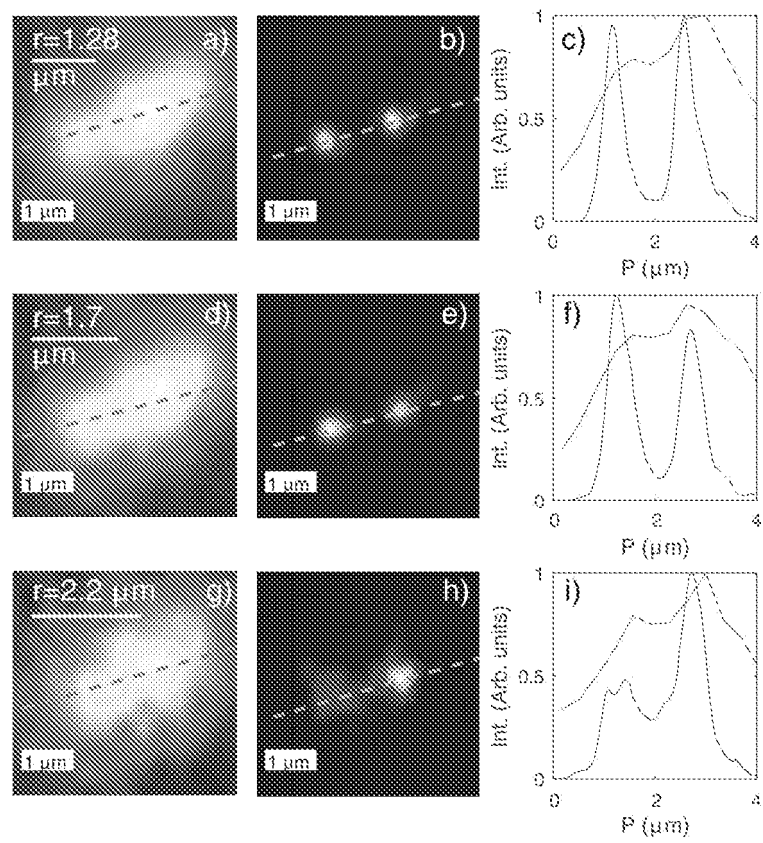


FIG. 4

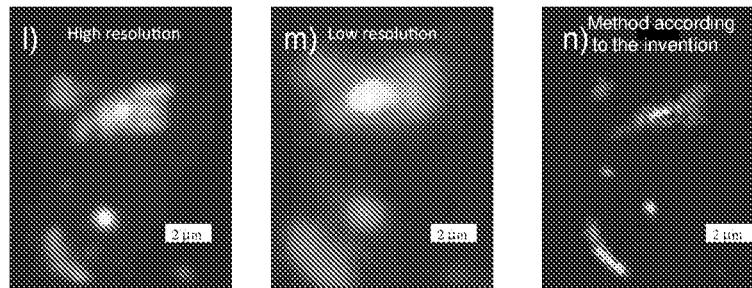


FIG. 5

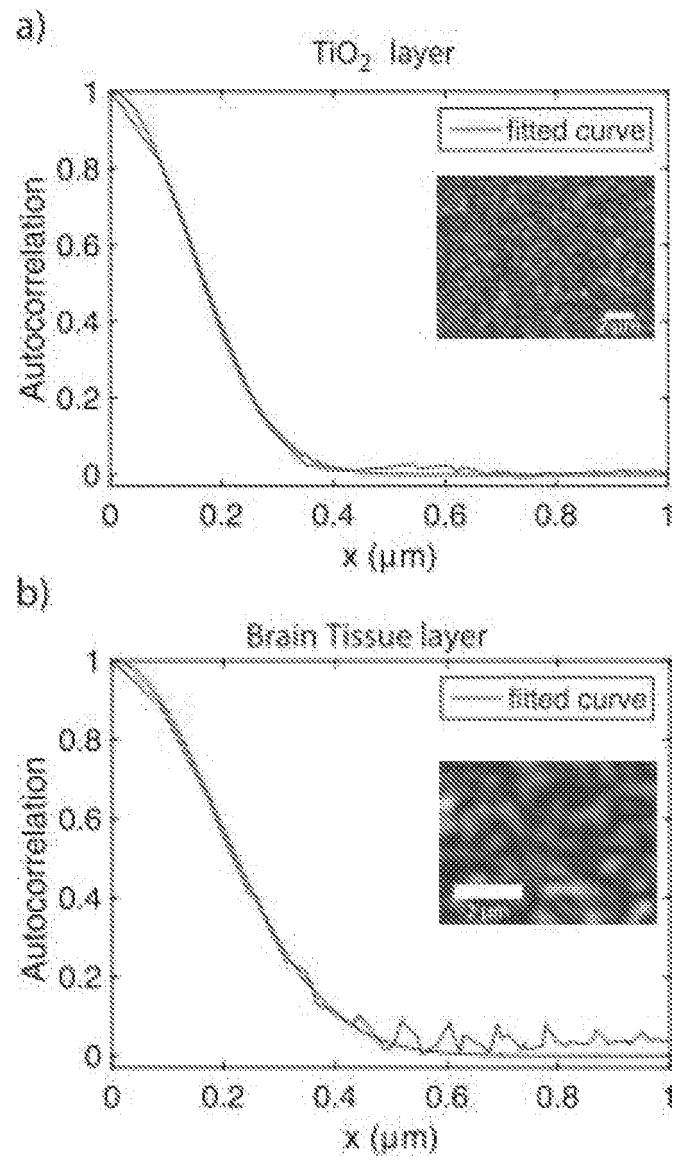


FIG. 6

REFERENCES CITED IN THE DESCRIPTION

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